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U.S. PATENT DOCUMENTS

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL	OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)
<i>TXL</i>	Hantschel, T., et al., "The fabrication of a full metal AFM probe and its applications for Si and InP device analysis", Proc. Micromachining and Microfabrication Conference, (1999).
<i>TXL</i>	Hantschel, T., et al., "Fabrication and use of metal tip and tip-on-tip probes for AFM-based device analysis", Proc. of SPIE, 3512, pp. 92-103, (1998)
<i>TXL</i>	Hantschel, T., et al., "The peel-off probe: a cost-effective probe for electrical atomic force microscopy", Proc. SPIE, vol. 4175, pp. 50-59, (September 18-19, 2000)
	Rasmussen, J., et al., "Fabrication of an all-metal atomic force microscope probe", Proc. of Transducers 1997, pp. 463-466, (1997)

EXAMINER

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